



MEMC 2512.2 (TP-98-3052)
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Robert J. Falster Art Unit 2811
Serial No. 10/038,084
Filed January 3, 2002
Confirmation No. 7363

For SILICON ON INSULATOR STRUCTURE HAVING A LOW DEFECT DENSITY
DEVICE LAYER AND A PROCESS FOR THE PREPARATION THEREOF

Examiner Anh D Mai

June 28, 2004

**NOTICE OF APPEAL FROM THE PRIMARY EXAMINER
TO THE BOARD OF PATENT APPEALS AND INTERFERENCES**

COMMISSIONER FOR PATENTS
P.O. BOX 1450
ALEXANDRIA, VIRGINIA 22313-1450

SIR:

Applicant hereby appeals to the Board of Patent Appeals and Interferences from
the decision of the Examiner dated January 28, 2004, rejecting the following claims: 47-
52.

- * The appeal fee of \$330.00 is submitted herewith.
 - * The fee for an extension of time under 37 CFR 1.136(a) is also enclosed.
- If there are any additional charges in this matter, please charge our Deposit
Account No. 19-1345.

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02 FC:1401 330.00 DP

Respectfully submitted,

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